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Seventh European Seminar on Precision Optics Manufacturing

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Freeform optics cannot be manufactured by standard spherical or aspheric manufacturing techniques. They can embody a wide range of geometries, offering great advantages over conventional shapes to a wide range of applications. Jährlich findet am Technologie Campus Teisnach das Optikseminar "European Seminar on Precision Optics Manufacturing" statt. Die zweitägige Fachkonferenz im ersten Halbjahr bietet Experten für Fertigungstechnik im Bereich Präzisionsoptik eine Plattform zur Diskussion über neue Erkenntnisse und Lösungsansätze. Fifth European Seminar on Precision Optics Manufacturing, edited by Rolf Rascher, Christian Schopf, Proc. of SPIE Vol. 10829, 1082905 © 2018 SPIE CCC code: 0277-786X/18/\$18 doi: 10.1117/12.2317630. Proc. of SPIE Vol. 10829 1082905-1 Downloaded From: <https://www.spiedigitallibrary.org/conference-proceedings-of-spie> on 8/7/2018 Terms of Use: <https://www.spiedigitallibrary.org/terms-of-use>. 1 Select. When fabricating high precision optical components, one of the performance characteristics of optical metrology instruments is the ability to detect and accurately measure mid- and high-spatial frequency surface deviations from the ideal figure. The demand to extend the instrument measurement range have driven camera formats to higher and higher density. PROCEEDINGS VOLUME 11478 new. Seventh European Seminar on Precision Optics Manufacturing. Editor(s): Oliver W. Hnle; Gerald Watterer; Rolf Rascher; Alexander Haberl. For the purchase of this volume in printed format, please visit [Proceedings.com](https://www.spiedigitallibrary.org/terms-of-use). We report on a photonic process chain to manufacture optical elements by non-contact all laser based micro-processing. Firstly, pre-defined optics geometries are generated by high-precision 1030 nm femtosecond layer-by-layer ablation. In order to meet high surface quality requirements, inevitable stipulated for optical use, the surface of thus generated elements has to be smoothed by subsequent 10.6 µm CO2 laser polishing. Centre for Optical Technologies. Institution: Hochschule Aalen. Department: Faculty of Optics and Mechatronics. Overview. Featured projects (1). Vreiform - Virtueller und realer polierprozess zur Herstellung von Freiformwerkzeugen im Formenbau. Project. View. Advance your research. Seventh European Seminar on Precision Optics Manufacturing. View. Download. 224 Reads. Lab head. Rainer Boerret. Hochschule Aalen. Fifth European Seminar on Precision Optics Manufacturing. 10 April - 11 April. (POM18), Teisnach, Germany. Glass and Optical Materials Division Meeting (GOMD 2018), San Antonio, Texas, USA. 20 May - 24 May. Andrea Silnes, The American Ceramic Society, 600 N. Cleveland Ave.